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Substitute for form 1449A/PTO  
**INFORMATION DISCLOSURE  
 STATEMENT BY APPLICANT**  
*(Use as many sheets as necessary)*

Complete if Known

Application Number	10/820,911
Filing Date	April 8, 2004
First Named Inventor	Littau, Michael
Group Art Unit	2877
Examiner Name	Gordon J. Stock, Jr.

Sheet 1 of 2

Attorney Docket No: 31162-1011

**US PATENT DOCUMENTS**

Examiner Initial	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
JD	US-4,710,642	12/01/1987	McNeil, John R.	
JD	US-4,759,626	07/26/1988	Kroko, Catherine G.	
JD	US-4,863,548	09/05/1989	Lee, Won-Sik	
JD	US-4,920,273	04/24/1990	Sacks, Jack , et al.	
JD	US-5,044,750	09/03/1991	Shamble, Edward M.	
JD	US-5,164,790	11/17/1992	McNeil, John R., et al.	
JD	US-5,241,369	08/31/1993	McNeil, John R., et al.	
JD	US-5,266,790	11/30/1993	Markle, David A., et al.	
JD	US-5,703,692	12/30/1997	McNeil, John R., et al.	
JD	US-5,712,707	01/27/1998	Ausschnitt, Christopher P., et al.	
JD	US-5,867,276	02/02/1999	McNeil, John R., et al.	
JD	US-5,877,860	03/02/1999	Borden, Peter G.	
JD	US-5,889,593	03/30/1999	Bareket, Noah	
JD	US-5,912,741	06/15/1999	Carter, Ron R., et al.	
JD	US-5,952,132	12/12/1997	King, Mingchu , et al.	
JD	US-5,953,128	09/14/1999	Ausschnitt, Christopher P., et al.	
JD	US-6,005,669	12/21/1999	Pahk, Heui J., et al.	
JD	US-6,088,113	07/11/2000	Kim, Young-chang	
JD	US-6,100,985	08/08/2000	Scheiner, David , et al.	
JD	US-6,429,930	08/06/2002	Littau, Michael E., et al.	
JD	US-6,606,152	08/12/2003	Littau, Michael E., et al.	
JD	US-6,728,663	04/27/2004	Kruk, Richard H., et al.	
JD	US-US2002/0038196	03/28/2002	Johnson, Kenneth C., et al.	
JD	US-US2002/0131055	09/19/2002	Niu, Xinhui , et al.	
JD	US-US2002/0135783	09/26/2002	Opsal, Jon , et al.	

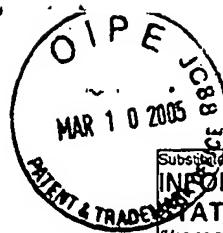
EXAMINER

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Substitute Disclosure Statement Form (PTO-1449)

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Substitute for form 1449A/PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <small>(Use as many sheets as necessary)</small>		Complete if Known	
		<b>Application Number</b>	10/820,911
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		<b>Examiner Name</b>	Gordon J. Stock, Jr.
Sheet 2 of 2		Attorney Docket No: 31162-1011	

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>2</sup>
180	WO-WO 01/97279 A2	12/20/2001	Miller, Michael L., et al.		
180	WO-WO 03/032085	04/17/2003	Littau, Michael E., et al.		

OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			
926		AUSSCHNITT, CHRISTOPHER P., et al., "Seeing the forest for the trees: a new approach to CD control", Proc. SPIE Vol. 3332, (1998), 212-220			
926		BAO, JUNWEI, et al., "A Focus Tests based on Scatterometry", <u>Slide Presentation</u> , <a href="http://bcam.berkeley.edu/archive/ilp98/junwei/1.html">http://bcam.berkeley.edu/archive/ilp98/junwei/1.html</a> , Berkeley Computer Aided Manufacturing, University of California at Berkeley, Berkeley, CA., (March 1998),			
180		EDWARDS, RICK, et al., "Characterization of Autofocus Uniformity and Precision on ASML Steppers using the Phase Shift Focus Monitor Reticle", <u>Proc. SPIE</u> Vo. 3051, (1997), 448-455			
926		NIU, X., et al., "In-Situ Sensing by Specular Spectroscopic Scatterometry", <u>Slide Presentation</u> , <a href="http://www.bcam.eecs.berkeley.edu/archive/ilp98/junwei/1.html">http://www.bcam.eecs.berkeley.edu/archive/ilp98/junwei/1.html</a> , Berkeley Computer Aided Manufacturing, University of California at Berkeley, Berkeley, CA., (March, 1998),			
180		NIU, XINHUI, et al., "Specular Spectroscopic Scatterometry in DUV Lithography", <u>Proc. SPIE Metrology, Inspection, and Process Control for Microlithography XIII</u> , Vol. 3677, SPIE, Santa Clara, California, (March, 1999), 159-168			
180		RAYMOND, CHRISTOPHER J., et al., "Angle-resolved scatterometry for semiconductor manufacturing", <u>Microlithography World</u> , (Winter 2000), 18-23			

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